

#### **Decoders 1.1: Introduction to Microfabrication**

**Style:** *Individual;* Personal

This class is graded P/D/F. To pass, you must: (i) attend all the cleanroom sessions, (ii) complete the sections of edX course and all the quizzes as outlined in the syllabus (progress will be checked and noted every week.), and (iii) define all microfabrication terms given in the classroom. By the end of Class #1, students must decide whether to register or drop the course.

**Overview:** In *Decoders 1.1*, cleanroom processes and fabrication techniques are aimed to be learned through lectures in class and then in cleanroom. At the end of each class, microfabrication terms are given to students to be defined. In the next class, students work together to explain these terms with associated sketches and analogies. The information is then collected in the class booklet. Students will gain handson experience with all six components of the microfabrication techniques including cleaning, deposition, patterning, etching, transfer printing and testing. The midterm project is to create a video of a microfabrication process (in groups of two or three) taught in the cleanroom and posted on the course website and YouTube channel. The final project is to identify a problem that can be tackled with a collective device fabricated in the cleanroom, which is the focus of *D1.2*.

- For homework, register Micro and Nanofabrication (MEMS) course at <a href="https://www.edx.org/course/micro-nanofabrication-mems-epflx-memsx-0">https://www.edx.org/course/micro-nanofabrication-mems-epflx-memsx-0</a>
- <u>Cleanroom</u> (YellowBox) open hours will be held on Tuesdays and Fridays from 9am to 11am.

#### **Objectives:**

- 1. To learn various cleanroom processes in the classroom setting,
- 2. To re-define the microfabrication terms learned in the classroom,
- 3. To experience the microfabrication processes in the cleanroom,
- 4. To create video clips of these processes with a personal style.



#### Schedule:

## Class 1: September 6<sup>th</sup>, 2018 (E15-466 & E15-443a)

- a. Overview and introduction to microfabrication, cleanrooms, and processes:
  - i. *Lecture*: Microfabrication principles, comparison of technologies, fabrication phases.
    - 1. Six components of microfabrication cleaning, deposition, patterning, etching, transfer printing, testing.
    - 2. Silicon, Other elemental or compound semiconductor, metals, glasses, quartz, sapphire, ceramics, plastics/polymers.
  - ii. *Lab*: Gowning, PPE procedure in the cleanroom. Particle contamination, contamination measurement, cleanroom chemistry and concepts.

#### (Group RED in charge of recording)

- iii. Substrate fabrication: Si: Poly, single crystal dicing.
- iv. Provide microfabrication terms to be defined.
- v. HW: Take the "MEMS and cleanroom introduction" section of edX Course and complete all online quizzes.
- vi. HW: Take the "Lithography" section of edX Course and complete all online quizzes.

# Class 2: September 13<sup>th</sup>, 2018 (E15-466)

- b. Patterning
  - vii. HWs will be checked.
  - viii. Work collectively on microfabrication terms given in Class #1.
  - ix. Lecture: Lithography, photoresist.
  - x. Provide microfabrication terms to be defined.

### Class 3: September 20<sup>th</sup>, 2018 (E15-443a)

- c. Patterning
  - xi. Work collectively on microfabrication terms given in Class #2.

    Lab: Process steps, +/- resist, coating, developing, removing, contact and proximity exposure, projection, alignment and marks, light sources.

    (Group YELLOW in charge of recording)
  - xii. Provide microfabrication terms to be defined.
  - xiii. HW: Take the "Chemical vapor deposition (CVD)" section of edX Course and complete all online guizzes.
  - xiv. HW: Take the "Physical vapor deposition (PVD)" section of edX Course and complete all online quizzes.



### Class 4: September 27<sup>th</sup>, 2018 (E15-466)

- d. Design parameters and considerations for devices
  - xv. HWs will be checked.
  - xvi. Work collectively on microfabrication terms given in Class #3.
  - xvii. Lecture: Device requirements, environmental impact, cost factor.
- e. Deposition
  - xviii. Lecture: Thermal oxidation, Physical Vapor deposition (sputtering and E-beam), Chemical vapor deposition (CVD and PECVD), Atomic layer deposition (ALD), Epitaxy (vapor and liquid).
  - xix. Provide microfabrication terms to be defined.
  - xx. HW: Take the "Dry etching" section of edX Course and complete all online quizzes.
  - xxi. HW: Take the "Wet etching" section of edX Course and complete all online quizzes.

### Class 5: October 4<sup>th</sup>, 2018 (E15-466)

- f. Etching
  - xxii. HWs will be checked.
  - xxiii. Work collectively on microfabrication terms given in Class #4.
  - xxiv. Lecture: Wet etch, dry etch.
  - xxv. Provide microfabrication terms to be defined.

### Class 6: October 11th, 2018 (E15-443a)

- g. Etching
  - xxvi. Work collectively on microfabrication terms given in Class #5.
  - xxvii. *Lab*: Practicing etching.

(Group GREEN in charge of recording)

xxviii. Provide microfabrication terms to be defined.

# Class 7: October 18th, 2018 (E15-466)

- h. Transfer printing
  - xxix. Work collectively on microfabrication terms given in Class #6.
  - xxx. *Lecture*: Surface energy, adhesion and release dynamics, delamination velocity and surface energy release rate.
  - xxxi. Provide microfabrication terms to be defined.



# Class 8: October 25th, 2018 (E15-443a)

i. Transfer printing

xxxii. Work collectively on microfabrication terms given in Class #7.

xxxiii. *Lab*: Students one by one practice transfer printing with automatic, transfer printing tool.

(Group BLUE in charge of recording)

xxxiv. Provide microfabrication terms to be defined.

**xxxv.** *HW: Take the "Inspection and metrology" section of edX Course and complete all online quizzes.* 

#### Class 9: November 1st, 2018 (E15-466 & E15-443a)

j. Packaging and testing

xxxvi. HW will be checked.

xxxvii. Work collectively on microfabrication terms given in Class #8.

xxxviii. *Lecture*: Surface characterization, ACF cabling, electrical characterization/measurements.

xxxix. Lab: Probe station, microscopy, laser vibrometer.

(Group VIOLET in charge of recording)

xl. Provide microfabrication terms to be defined.

### Class 10: November 8<sup>th</sup>, 2018 (E15-466)

k. Internal feedback for the videos

xli. Lecture: Wrap up.

xlii. Defining the problem that is going to be tackled in the next course (D1.2).

xliii. Forming the booklet consists of defined microfabrication terms.

xliv. Suggestions for future class.

# Class 11: November 15<sup>th</sup>, 2018 (E15-466)

I. Lecture: Final video presentation (internally, to the PI).

### Class 12: November 29<sup>th</sup>, 2018 (E15-466)

m. Video Editing & Publishing



# Class 13: December 6<sup>th</sup>, 2018 (E15-070, 5-6pm, Bartos Theater)

- n. Project
  - xlv. Presentations and demo open to the Media Lab.
  - xlvi. Video contest at Media Lab.

### Calendar

September 2018								October 2018								November 2018							December 2018						
Su	Мо	Tu	We	Th	Fr	Sa		Su	Мо	Tu	We	Th	Fr	Sa		Su	Мо	Tu	We	Τh	Fr	Sa	Su	Мо	Tu	We	Th	Fr	Sa
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16	17	18	19	20	21	22		21	22	23	24	25	26	27		18	19	20	21	22	23	24	16	17	18	19	20	21	22
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